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## ***Subdiffraction-limited Plasmonic Lithography and Innovative Manufacturing Technology***

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# Contents

|      |                             |
|------|-----------------------------|
| vii  | <i>Authors</i>              |
| xi   | <i>Symposium Committees</i> |
| xiii | <i>AOMATT 2018 Sponsors</i> |

## **SUBDIFFRACTION-LIMITED PLASMONIC LITHOGRAPHY AND INNOVATIVE MANUFACTURING TECHNOLOGY**

---

|          |  |
|----------|--|
| 10842 02 | <b>A Hermitian symmetry based OFDM signal transmitter for digitized radio-over-fiber transmission [10842-1]</b>                                    |
| 10842 03 | <b>Research on temperature distribution and thermal stress of laser crystal from self-Raman yellow laser [10842-2]</b>                             |
| 10842 04 | <b>Negative capacitance transistors with sub-kT/q swing [10842-3]</b>  |
| 10842 05 | <b>Feature extraction of acoustic emission signals in diamond scratching of brittle materials based on shift-invariant sparse coding [10842-5]</b> |
| 10842 06 | <b>An experimental platform for rapid melting and solidification of metal materials in space [10842-6]</b>   |
| 10842 08 | <b>3D printing of hypothetical brick by selective laser sintering using lunar regolith simulant and ilmenite powders [10842-9]</b>                 |
| 10842 09 | <b>Controllable wettability of metallic surfaces via micro-nano structure fabricated by femtosecond laser [10842-10]</b>                           |
| 10842 0A | <b>Analysis on the evolution of subwavelength ripples fabricated by ultrafast laser pulses on lithium niobate crystal surface [10842-11]</b>       |
| 10842 0B | <b>Additive manufacturing of millimeter-scale micron-accuracy 3D structures [10842-12]</b>   |
| 10842 0C | <b>Biocompatible three-dimensional hydrogel microstructures fabricated by two-photon polymerization [10842-13]</b>                                 |
| 10842 0D | <b>The luminance measurement model of LED display using the image sensors [10842-15]</b>   |
| 10842 0E | <b>Three-dimensional micro-cones fabricated via two-photon photolithography [10842-16]</b>   |
| 10842 0F | <b>Surfactant mediated synthesis of structured metal nanoparticle by pulsed laser ablation for photocatalysis [10842-17]</b>                       |
| 10842 0G | <b>Multi-photon laser lithography of AR-N 4340 photoresist with a spatial resolution at nanoscale [10842-19]</b>                                   |

- 10842 OH **Structural modifications induced by ultrafast IR laser pulses in sapphire** [10842-20]
- 10842 OI **Structural modeling and strength characteristics of optical system in strong impact environment** [10842-21]
- 10842 OJ **Integration of functional microstructures inside a microfluidic chip by direct femtosecond laser writing** [10842-22]
- 10842 OK **Investigation on the nonlinear relationship between relative velocity and material removal in bonnet polishing** [10842-23]
- 10842 OL **Advanced metal-wire laser additive manufacturing in-space** [10842-24]
- 10842 OM **Research on hand-eye calibration method based on stereo vision for harvesting robot** [10842-25]
- 10842 ON **Fabrication of superhydrophobic magnesium alloy surface for water repellent** [10842-26]
- 10842 OO **Liquid bridge simulation of metal-wire laser additive manufacturing in microgravity environment** [10842-27]
- 10842 OP **A true-color nano-CT based on SEM** [10842-33]
- 10842 OQ **A high-precision optical fiber adaptive lithography method for vertical integration of optical fiber and planar chip** [10842-38]
- 10842 OR **Large area transparent organic light-emitting device by using PFN modified ZnO as electron transfer layer** [10842-52]
- 10842 OS **Ion beam figuring high gradient optical aspherical surface** [10842-53]
- 10842 OT **Organic-inorganic hybrid perovskite photodetectors achieved via brush-coating process** [10842-57]
- 10842 OU **Relationship between slurry flow pattern and removal characteristic based on a novel polishing tool** [10842-70]
- 10842 OV **Computer-aided NC programming system for large scale and off-axis aspheric optics in parallel grinding** [10842-72]
- 10842 OW **Parameters selection for different metals in coating thickness measurement using x-ray fluorescence analysis** [10842-77]
- 10842 OX **Fabrication and optical properties of Er-doped ZnO thin films** [10842-78]
- 10842 OY **Influence of liquid crystal alignment material and technology on phase modulation of liquid crystal microwave phase shifter** [10842-79]
- 10842 OZ **Damage resistance of fused silica modified by magnetorheological finishing (MRF) and ion beam etching (IBE)** [10842-91]

- 10842 10 **Enhancing the wettability of PEDOT:PSS layer with plasma treatment method in perovskite solar cells** [10842-99]
- 10842 11 **Fabrication of small cylindrical lens** [10842-111]
- 10842 12 **Precision manufacturing technology of axicon** [10842-120]
- 10842 13 **Laser generation of ultrasound in adhesively bonded three-layered plate** [10842-123]
- 10842 14 **Ultra-precision robotic sub-aperture polishing of curved mirrors** [10842-137]
- 10842 15 **Enhancing performance of inverted organic solar cells by nano-imprinting the active layer with a PDMS template** [10842-150]
- 10842 16 **Study of optic and laser-induced damage properties of Ta<sub>2</sub>O<sub>5</sub> films deposited by different process parameters** [10842-216]
- 10842 17 **A preliminary study of in-situ defects measurement for additive manufacturing based on multi-spectrum** [10842-225]
- 10842 18 **Kilo-joule back lighting terminal system** [10842-261]
- 10842 19 **Analysis of computer-generated holographic microstructure fabricated by femtosecond laser** [10842-299]
- 10842 1A **Near field optical lithography using ultra-small gap bowtie apertures** [10842-503]
- 10842 1B **Design of bifocal compound eyes and gray mask fabrication based on maskless photolithography** [10842-508]
- 10842 1C **Double-beam laser interference lithography based on optical field modulation** [10842-521]
- 10842 1D **Fabrication of porous structures on microchannel surfaces by laser micromilling for enhanced microchannel heat sinks** [10842-08]